

## ABSTRACT OF THE DISCLOSURE

A non-volatile semiconductor memory cell structure and method of manufacture. The method includes the steps of forming a shallow first-type well layer, a second-type well layer and a deep first-type well layer over a substrate, forming stack gates over the  
5 shallow first-type well layer and finally forming source terminals and drain terminals. The source terminals penetrate through the shallow first-type well layer and connect with the second-type well layer. The drain terminals are close to the surface of the shallow first-type well layer. Both the source terminals and the drain terminals contain second type dopants.

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